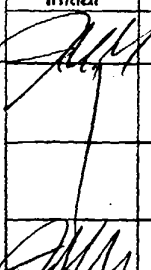
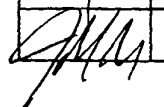
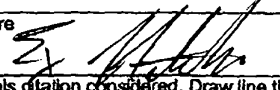


Substitute Form PTO-1449 (Modified) APR 08 2002 INFORMATION DISCLOSURE STATEMENT by Applicant (Use several sheets if necessary) (37 CFR 1.53(b))	U.S. Department of Commerce Patent and Trademark Office		Attorney's Docket No. 06618-720001	Application No. 10/005,765
	Applicant Eui-Hyeok Yang and Dean V. Wiberg			
	Filing Date November 2, 2001		Group Art Unit 2812	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
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	AE						
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	AH						
	AI						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
	AJ						Yes	No
	AK							
	AL							

Other Documents (Include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AM	K.F. Harsh, W. Zhang, V.M. Bright and Y.C. Lee, "Flip-Chip Assembly for Si-Based RF MEMS", Proc. MEMS '99, Orlando, Florida, pp. 273-278, Jan 1999
	AN	T. Akiyama, U. Stuzfer and N de Rooij, "Wafer-and Piece-Wise Si Tip Transfer Technologies for Applications in Scanning Probe Microscopy", IEEE Journal of Microelectromechanical Systems, pp. 65-70, 1999
	AO	A. Singh, D.A. Horsley, M. Cohn, A. Pisano and R.T. Howe, "Batch Transfer of Microstructures using Flip-Chip Solder Bonding", IEEE Journal of Microelectromechanical Systems, pp. 27-33 1999.
	AP	H. Nguyen, P. Patterson, H. Toshiyoshi and M.C. Wu, "A Substrate-Independent Wafer Transfer Technique for Surface-Micromachined Devices", Proc MEMS Conference, 2000

Examiner Signature 	Date Considered 6/20/02
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 06618-720001	Application No. 10/005,765
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		Filing Date November 2, 2001	Group Art Unit 2812

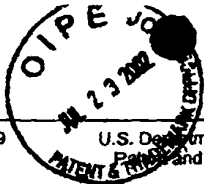
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							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
<i>[Signature]</i>	AQ	TE Bell and KD Wise, "A dissolved wafer process using a porous silicon..." Proc MEMS 98, Heidelberg Germany, 25-29, Jan 1998, pp. 251-256.
<i>[Signature]</i>	AR	CG Keller and RT Howe, "Hexile tweezers for teleoperated micro-assembly", Proc MEMS 97, Nagoya, Japan, 1997 pp. 72-77.
	AS	
	AT	

Examiner Signature <i>[Signature]</i>	Date Considered 6/30/03
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	Applicant Eui-Hyeok Yang and Dean V. Wiberg		
	Filing Date November 2, 2001		Group Art Unit 2812

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>[Signature]</i>	AA	4 383 886	May 17, 1983	Nakamura et al.			
	AB	4 700 467	Oct 20, 1987	Donzelli			
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